Epitaxial growth and properties of ε-Ga₂O₃ thin films

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The possibility of growing high-quality gallium oxide (Ga_2O_3) single crystals and films has triggered a great interest on this materials, as very promising candidate for applications in new areas such as high-power transistors and UV detectors.

Although the homo-epitaxy is possible, most research on Ga_2O_3 thin films is still carried out on heterosubstrate such as sapphire. Despite the relatively quick advancements of the last few years, there are still many open questions regarding the deposition of Ga_2O_3 on foreign substrates, for instance related to the appearance of different crystallographic phases: beta (monoclinic), alfa (hexagonal), gamma (cubic), delta (cubic) and epsilon (hexagonal/orthorhombic).

This talk will focus on the recent advancements in epitaxial growth ε -Ga₂O₃ [1] and the extensive characterization by X-ray, TEM, photo-conductivity and absorption spectroscopy. The interest in ε phase arises from the possibility of coupling its high energy gap, similar to that of the more popular β -Ga₂O₃, with less critical growth conditions, for example a much lower deposition temperature. Moreover, ε -Ga₂O₃ films provide a more advantageous crystallographic symmetry than monoclinic β -Ga₂O₃ and can be easily deposited on c-oriented sapphire and gallium nitride, which is good in view of developing a novel oxide-nitride technology. The growth of ε -Ga₂O₃ was seen to proceed via generation of small oriented nuclei that later expand to produce large hexagonal islands (size of 200-400 nm), which ultimately merge producing a flat and homogeneous film. Under appropriate growth conditions, epilayers of the same ε -Ga₂O₃ phase were also successfully deposited on alternative hetero-substrates such as (0001)-GaN and (111)-SiC with good results. The major disadvantage of the epsilon phase comes from its intrinsic instability: it tends to convert to monoclinic beta when annealed above 700 °C. Nevertheless, this is a relatively high value, which in principle enables the use of hexagonal Ga₂O₃ for device fabrication.

[1] F. Boschi, M. Bosi, T. Berzina, E. Buffagni, C. Ferrari, R. Fornari, J. Cryst. Growth 443 (2016) 25